Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) An apparatus for outputting a laser beam comprising:

a laser beam source;

laser beam diameter adjusting means for adjusting a diameter of a beam incident from said laser beam source;

laser beam reflecting direction controlling means for controlling a reflecting direction of the beam incident from said laser beam diameter adjusting means; and

recording means for recording information data in accordance with said diameter of ~~the~~ said beam incident from said laser beam ~~reflection~~ reflecting direction controlling means.

2. (Currently Amended) The apparatus according to claim 1, wherein said laser beam diameter adjusting means comprises:

a piezoelectric/electrostrictive film ~~type~~ element comprising:

_____a substrate;

_____a piezoelectric/electrostrictive operating section integrated onto said substrate; and

_____a reflective surface associated with said piezoelectric/electrostrictive film ~~type~~ element.

3. (Currently Amended) The apparatus according to claim 2, wherein said substrate of ~~the~~ said piezoelectric/electrostrictive film ~~type~~ element ~~has~~ comprises a ~~relatively~~ thin ~~and~~, flexible sheet section and a peripheral section surrounding said sheet section, said peripheral section being relatively rigid and thicker than said sheet section, and wherein said piezoelectric/electrostrictive operating section is arranged on said sheet section of ~~the~~ said substrate.

4. (Currently Amended) The apparatus according to claim 3, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on said sheet section;

a piezoelectric/electrostrictive layer arranged on said first electrode;

a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode; and

wherein said reflective surface ~~is formed by~~comprises a layer ~~that is~~ arranged on said second electrode.

5. (Currently Amended) The apparatus according to claim 3, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on one face of said sheet section;

a piezoelectric/electrostrictive layer arranged on said first electrode;

a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode; and

wherein said reflective surface ~~is formed by~~comprises a layer ~~that is~~ arranged on the other face of said sheet section.

6. (Currently Amended) The apparatus according to claim 3, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on said sheet section;

a piezoelectric/electrostrictive layer arranged on said first electrode; and

a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode, wherein said second electrode ~~forms~~ comprises said reflective surface.

7. (Currently Amended) The apparatus according to claim 1, further comprising at least one of:

a first optical system arranged in an optical path between said laser beam source and said laser beam diameter adjusting means; and

a second optical system arranged in an optical path between said laser beam reflecting direction controlling means and said recording means.

8. (Currently Amended) An apparatus for outputting a laser beam comprising:

a laser beam source;

laser beam diameter adjusting means for adjusting a diameter of a beam incident from said laser beam source;

laser beam reflecting direction controlling means for controlling a reflecting direction of ~~the~~ said beam incident from said laser beam diameter adjusting means; and

recording means for recording information data in accordance with said diameter of the beam incident from said laser beam ~~reflection~~ reflecting direction controlling means;

wherein said laser beam diameter adjusting means comprises:

____ a piezoelectric/electrostrictive film ~~type~~ element comprising:

_____a substrate;

_____a piezoelectric/electrostrictive operating section integrated onto said substrate; and

_____a reflective surface associated with said piezoelectric/electrostrictive film ~~type~~ element.

9. (Currently Amended) The apparatus according to claim 8, wherein said substrate of ~~the~~ said piezoelectric/electrostrictive film ~~type~~ element has a ~~relatively thin and~~, flexible sheet section and a peripheral section surrounding said sheet section, said peripheral section being relatively rigid and thicker than said sheet section, and wherein said piezoelectric/electrostrictive operating section is arranged on said sheet section of ~~the~~ said substrate.

10. (Currently Amended) The apparatus according to claim 9, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on said sheet section;

a piezoelectric/electrostrictive layer arranged on said first electrode;

a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode; and

wherein said reflective surface ~~is formed by~~comprises a layer ~~that is~~ arranged on said second electrode.

11. (Currently Amended) The apparatus according to claim 9, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on one face of said sheet section;

a piezoelectric/electrostrictive layer arranged on said first electrode;

a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode; and

wherein said reflective surface ~~is formed by~~comprises a layer ~~that is~~ arranged on the other face of said sheet section.

12. (Currently Amended) The apparatus according to claim 9, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on said sheet section;

a piezoelectric/electrostrictive layer arranged on said first electrode; and

a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode, wherein said second electrode ~~forms~~ comprises said reflective surface.

13. (Currently Amended) The apparatus according to claim 8, further comprising at least one of:

a first optical system arranged in an optical path between said laser beam source and said laser beam diameter adjusting means; and

a second optical system arranged in an optical path between said laser beam reflecting direction controlling means and said recording means.